

Attorney Docket: 061063-0318214



IFW

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of:
NAKADA et al.

Confirmation Number: 5511

Application No.: 10/551,695

Group Art Unit: 1765

Filed: September 30, 2005

Examiner: AHMED, SHAMIM

Title: SILICON WAFER HEAT TREATMENT JIG, AND SILICON WAFER HEAT TREATMENT METHOD

REPLY TO RESTRICTION REQUIREMENT

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In reply to the Office Action dated October 4, 2007, Applicants hereby elect the invention of Group II, claims 3-4, drawn to a device for treating a wafer. This election is made without traverse.

Prompt examination and favorable consideration on the merits are respectfully requested.

Please charge any fees associated with the submission of this paper to Deposit Account Number 033975. The Commissioner for Patents is also authorized to credit any over payments to the above-referenced Deposit Account.

Respectfully submitted,

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Date: October 30, 2007
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